IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Inventor	Trung Tri Doan, et al.
Assignee	Micron Technology, Inc.
Priority Group Art Unit	2812
Priority Examiner	Jennifer M. Kennedy
Attorney's Docket No	MI22-2359
Title	Atomic Layer Deposition Methods

PRELIMINARY AMENDMENT

To: Mail Stop Patent Application

Commissioner for Patents

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Please enter the following amendments prior to examining the aboveidentified application.

<u>AMENDMENTS</u>